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ATMI-668

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re United States Patent Application of:		Docket No.:	ATMI-668 (7493)
Applicants:	RATH, Melissa K., et al.	Conf. No.:	4823
Application No.:	10/792,038	Art Unit:	1752
Date Filed:	March 3, 2004	Examiner:	LE, Hoa Van
Title:	COMPOSITION AND PROCESS FOR POST-ETCH REMOVAL OF PHOTORESIST AND/OR SACRIFICIAL ANTI- REFLECTIVE MATERIAL DEPOSITED ON A SUBSTRATE	Customer No.:	25559

FACSIMILE TRANSMISSION CERTIFICATE ATTN: Examiner Hoa V. LE Fax No. (703) 872-9306

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Tristan A. Fuierer	
April 27, 2005	
Date	

RESPONSE TO RESTRICTION REQUIREMENT IN APRIL 18, 2005 OFFICE ACTION IN U.S. PATENT APPLICATION NO. 10/792,038

Mail Stop Amendment Commissioner for Patents P.O. Box 1450 Alexandria, Virginia 22313-1450

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